

Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 246036US2		SERIAL NO. New Application	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Masato HIRAMATSU, et al.			
				FILING DATE Herewith		GROUP	
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
DHL	AK	2002-289865	10/04/2002	JAPAN (with English Abstract)			X
	AL						
	AM						
	AN						
	AO						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
DHL	AP	Shinya TSUDA, et al., "PREPARATION AND PROPERTIES OF HIGH-QUALITY a-Si FILMS WITH A SUPER CHAMBER (SEPARATED ULTRA-HIGH VACUUM REACTION CHAMBER)", Japanese Journal of Applied Physics, Vol. 26, No. 1, January 1987, pgs. 33-38					
	AQ	C. C. TSAI, et al., "CLEAN" a-Si:H PREPARED IN A UHV SYSTEM", Journal of Non-Crystalline Solids, Vol. 66, 1984, pgs. 45-50					
	AR	Masato HIRAMATSU, et al., "AN ADVANCED PECVD SYSTEM FOR MASS-PRODUCING HIGH-PURITY Si THIN FILMS", IDW '02 Proceedings of the Ninth International Display Workshops, December 4-6, 2002, 2 pgs					
	AS	Masato HIRAMATSU, et al., "MECHANISM OF OXYGEN CONTAMINATION IN PECVD A-SI:H FILMS", Electrochemical Society Proceedings Volume 2003-08, pgs. 701-707					
	AT	Toshihiro KAMEI, et al., "DEPOSITION OF ULTRAPURE HYDROGENATED AMORPHOUS SILICON", J. Vac. Sci. Technol. A, Vol. 17, No. 1, Jan/Feb 1999, pgs. 113-120					
	AU	U. KROLL, et al., "ORIGINS OF ATMOSPHERIC CONTAMINATION IN AMORPHOUS SILICON PREPARED BY VERY HIGH FREQUENCY (70 MHz) GLOW DISCHARGE", J. Vac. Sci. Technol. A, Vol. 13, No. 6, Nov/Dec 1995, pgs. 2742-2746					
	AV	A. A. HOWLING, et al., "FREQUENCY EFFECTS IN SILANE PLASMAS FOR PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION", J. Vac. Sci. Technol. A, Vol. 10, No. 4, Jul/Aug 1992, pgs. 1080-1085					<input type="checkbox"/> Additional References sheet(s) attached
Examiner <i>Kang, Donghee</i>					Date Considered <i>04-06-05</i>		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							